



Docket No.: 50090-334

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Customer No. 20277
Masanobu IWASAKI, et al. : Confirmation No.
Serial No.: 09/934,474 : Group Art Unit: 3723
Filed: August 23, 2001 : Examiner: H. Shakeri

For: POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF SUPPLYING
POLISHING SOLUTION, APPARATUS FOR AND METHOD OF POLISHING
SEMICONDUCTOR SUBSTRATE AND METHOD OF MANUFACTURING
SEMICONDUCTOR DEVICE

PATENT

AF-14
3700
g-12-04
#16
EAF (2)

**RESPONSE TO ORDER RETURNING UNDOCKETED APPEAL TO
EXAMINER**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:
02/12/2004 ECOLBERT 00000005 500417 09934474
01 FC-2252 410.00 DA

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REMARKS

In the Order Returning Undocketed Appeal to Examiner mailed May 20, 2003, the Administrator Han asserted that the Notice of Appeal was filed on September 4, 2002, which exceeded three months from the date of the April 18, 2002 final Office Action. Administrator Han then suggested the case should have been abandoned. Appellants disagree.

As apparent from the PAIR file contents history, the Request for Extension of Time was granted after the Notice of Appeal was filed with a two-month extension. Accordingly, the case should **not** be abandoned as asserted by Administrator Han. For the

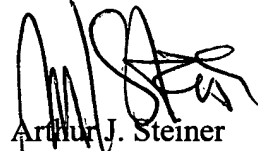
Administrator's convenience, a copy of the PAIR file and of a date-stamped card indicating the filing of a Notice of Appeal, request for a two-month extension and payment therefor are enclosed herewith.

Accordingly, the Administrator is requested to clarify the record by indicating that this application is not abandoned.

To the extent necessary, a petition for an extension of time under 37 C.F.R. 1.136 is hereby made. Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

MCDERMOTT, WILL & EMERY



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Date: November 17, 2003
Facsimile: (202) 756-8087



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Applicant:

Masanobu IWASAKI, et al.

Docket No.

50090-334

Title:

POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF
SUPPLYING POLISHING SOLUTION, APPARATUS FOR AND
METHOD OF POLISHING SEMICONDUCTOR SUBSTRATE AND
METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

Serial/Reg./Patent No.

09/934,474

Date Sent:

9/4/2002

☐ Hand Carried

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☐ Electronic

☐ Cert. of Mailing

☐ Express Mail No.

☐ Transmittal Letter

☐ New Patent App

☐ Utility

☐ Design

☐ Cont.

☐ CIP

☐ Div.

☐ PCT

☐ CPA

☐ RCE

☐ Prov

☐ Other:

pages of Specification

pages of Claims

pages of Abstract

pages of Formal/Informal Drawings

☐ Small Entity ☐ Large Entity

☐ Declaration/Power of Attorney

☐ Recordation of Assignment/Security Agreement

☐ Information Disclosure Statement

Form PTO 1449

copies of cited references

☐ Preliminary Amendment

☐ Response to Missing Parts Notice

☐ Resp. to Notice to Correct App. Papers

☐ Certified Copy of Priority Doc.

☐ Claim for Convention Priority

☐ Response/Amendment to Office Action of

☒ Request for 2 month Extension of Time

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Tjpr. #

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Secy. or Pl.

L. Renee Douglas

CMS Descrpt.: 9-\$320.00

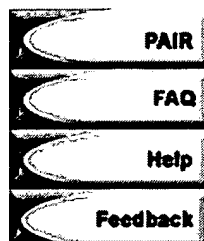
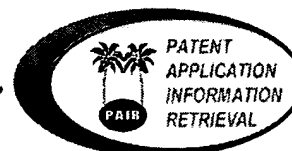
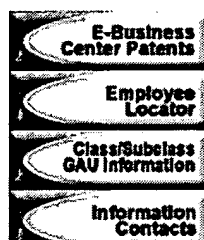
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THE PATENT AND TRADEMARK OFFICE DATE STAMPED HEREON IS ACKNOWLEDGEMENT THAT THE ITEMS, CHECKED ABOVE, WERE RECEIVED BY THE PTO ON THE DATE STAMPED.





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**PATENT APPLICATION INFORMATION RETRIEVAL****Other Links**

Search results for application number:09/934,474			
Application Number:	09/934,474	Customer Number:	-
Filing or 371(c) Date:	08-23-2001	Status:	Reply Brief Noted Examiner
Application Type:	Utility	Status Date:	03-17-2003
Examiner Name:	SHAKERI, HADI	Location:	TC 3700 CENTRAL CP2-10C25
Group Art Unit:	3723	Location Date:	10-20-2003
Confirmation Number:	8431	Earliest Publication No:	US 2002-0065022 /
Attorney Docket Number:	50090-334	Earliest Publication Date:	05-30-2002
Class/ Sub-Class:	451/041	Patent Number:	-
First Named Inventor:	Masanobu Iwasaki, Tokyo, (JP)	Issue Date of Patent:	-
Title Of Invention:	Polishing solution supply system, method of supplying polishing solution, apparatus for and method of polishing semiconductor substrate and method of manufacturing semiconductor device		

Continuity Data

Published Documents

File Contents History		
Number	Date	Contents Description
32	10-02-2003	Appeal Awaiting BPAI Docketing
31	05-20-2003	Order Returning Undocketed Appeal to the Examiner
30	04-22-2003	Appeal Awaiting BPAI Docketing
29	03-18-2003	Mail Reply Brief Noted by Examiner
28	03-17-2003	Reply Brief Noted by Examiner
27	01-27-2003	Date Forwarded to Examiner
26	01-22-2003	Reply Brief Filed
25	11-22-2002	Mail Examiner's Answer
24	11-21-2002	Examiner's Answer to Appeal Brief
23	11-14-2002	Date Forwarded to Examiner
22	11-04-2002	Appeal Brief Filed
21	09-04-2002	Notice of Appeal Filed
20	09-04-2002	Request for Extension of Time - Granted
19	07-26-2002	Mail Advisory Action (PTOL - 303)
18	07-26-2002	Advisory Action (PTOL-303)
17	07-25-2002	Date Forwarded to Examiner

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16	07-18-2002	Amendment after Final Rejection
15	04-18-2002	Mail Final Rejection (PTOL - 326)
14	04-16-2002	Final Rejection
13	03-13-2002	Date Forwarded to Examiner
12	03-04-2002	Response after Non-Final Action
11	12-04-2001	Mail Non-Final Rejection
10	11-28-2001	Non-Final Rejection
9	08-23-2001	Request for Foreign Priority (Priority Papers May Be Included)
8	08-23-2001	Information Disclosure Statement (IDS) Filed
7	10-29-2001	Case Docketed to Examiner in GAU
6	10-01-2001	Application Dispatched from OIPE
5	09-28-2001	Correspondence Address Change
4	09-28-2001	Correspondence Address Change
3	09-27-2001	Correspondence Address Change
2	08-29-2001	IFW Scan & PACR Auto Security Review
1	08-23-2001	Initial Exam Team nn

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